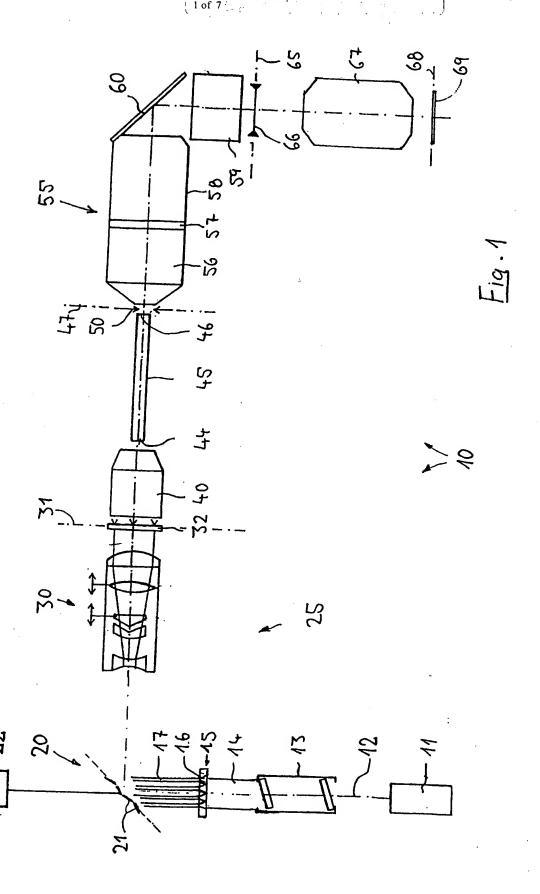
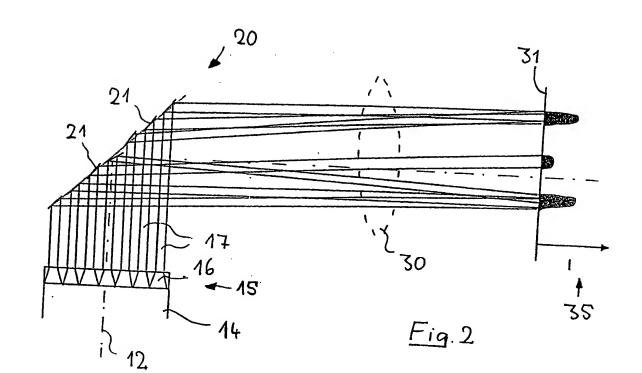
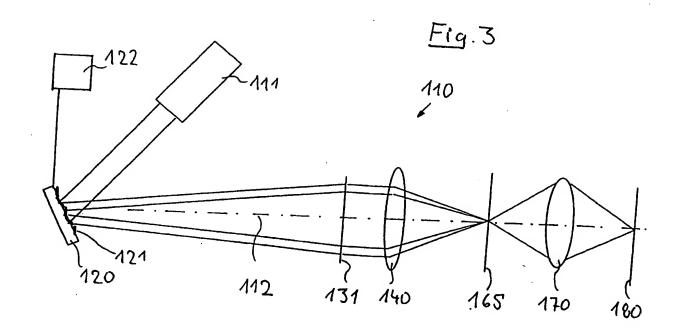
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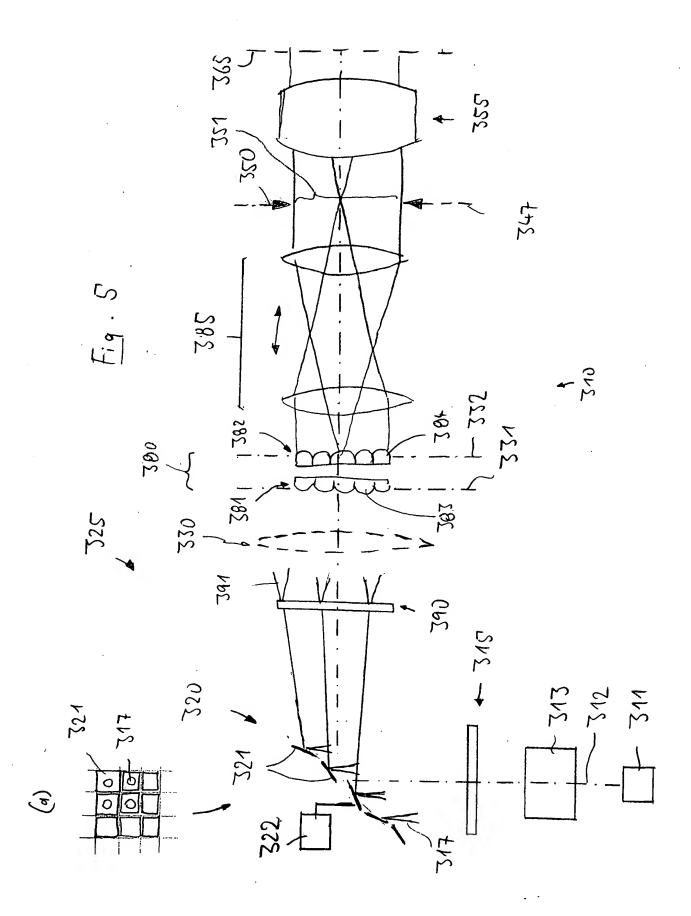


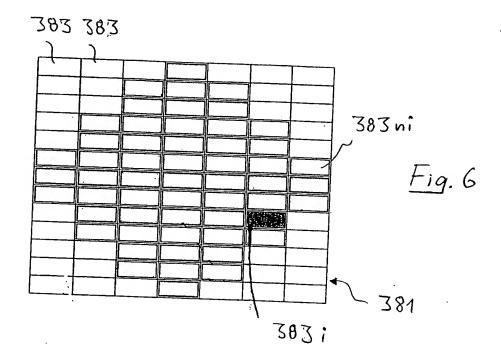


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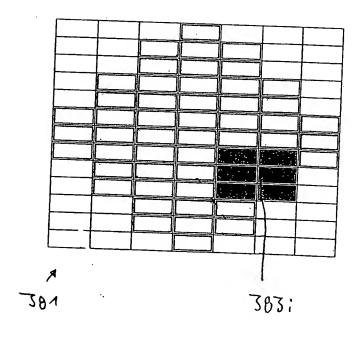
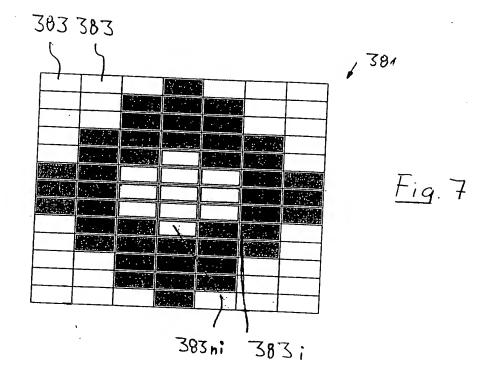
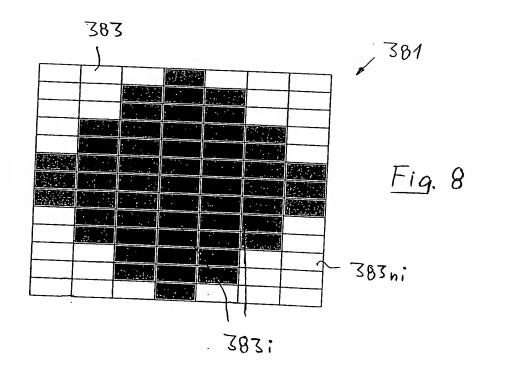


Fig. 9





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